JILA Keck Lab

W.M. Keck Optical Measurements Lab
JILA Micro and Nanofabrication Facility

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Optical Measurements Lab (Metrology Lab)

- The optical metrology lab contains a suite of instruments used to determine optical and surface properties of materials.
Optical and Surface Characterization

- Atomic Force Microscopes
- Ellipsometer
- Fizeau Interferometer
- FTIR
- UV-VIS-NIR Spectrophotometer
- Measuring Microscopes
- Optical Profilometer
Micro and Nanofabrication Facility (Clean Room)

- The JILA clean room consists of two Class 1000 (ISO 6) bays, one Class 100 (ISO 5) bay as well as a gowning and wipe-down area
- Micro and nano devices can be fabricated and measured in a critically controlled environment
Lithography Bay

- Mask Aligner/Exposer
- Spin Coaters
- Optical Microscope
- Developing/Solvent Cleaning Wet Bench
- Acid Etching Wet Bench
- Dedicated HF/KOH Etching Wet Bench
Fabrication Bay

- E-Beam and Thermal Deposition Systems
- Sputter Coating Chambers
- Reactive Ion Etcher
- Critical Point Drier
- Tube Furnace
- Wire Bonders
SEM Bay

- Scanning Electron Microscopes
- E-Beam Lithography
- Stylus Profilometer
- Four Point Probe
- Au/Pd Sputter Coater
Additional Tools

- Grinder/Polisher
- Crystal Saw
- Dicing Saw
- Fiber Cleaver
- Fiber Fusion Splicer
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